



09-28-05

MEMC 02-0051(3032.1)
PATENT

1FW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Henry F. Erk et al.
Serial No. 10/665,982
Filed September 18, 2003
Confirmation No. 5374
For PROCESS FOR ETCHING SILICON WAFERS
Examiner Eric Brice Chen

Art Unit 1765

September 27, 2005

COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450

SIR:

RESPONSE TO RESTRICTION REQUIREMENT

In response to the restriction requirement mailed September 2, 2005, Applicants elect to have the claims of Group I (claims 1-99) examined in the subject application. Applicants reserve the right to file one or more divisional applications directed to any of the non-elected claims.

Respectfully submitted,

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